

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535
First Named Inventor : Takuya SUGAWARA
Filed : June 28, 2004
TC/A.U. : 2823
Examiner : M. Estrada

Docket No. : 010986.55104US
Customer No. : 23911

Title : Substrate Treating Method and Production Method for
Semiconductor Device

REPLY

Mail Stop RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in accompaniment of a Request for Continued Examination and in response to the Final Office Action dated February 3, 2006, the period for response having been extended to July 3, 2006 by the attached Petition for Extension of Time.

Amendments to the Specification are discussed on page 2 of this paper. A Substitute Specification with marked-up version is submitted concurrently herewith.

Remarks begin on page 3 of this paper.

An **Appendix** including a substitute version of the specification, and a marked up version of the specification is attached following page 6 of this paper.